



Practitioner's Docket No. 081468-0307473
Client Reference: P-1795.000-US

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: VADIM YEVGENYEVICH BANINE et al.

Application No.: 10/748,851

Confirmation No.: 2813

Filed: December 31, 2003

Group No.: 2851

Examiner:

For: LITHOGRAPHIC APPARATUS HAVING A DEBRIS-MITIGATION SYSTEM,
A SOURCE FOR PRODUCING EUV RADIATION HAVING A DEBRIS MITIGATION
SYSTEM AND A METHOD FOR MITIGATING DEBRIS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL APPLICATION DATA SHEET
37 C.F.R. § 1.76(c)

The following information on the Application Data Sheet is changed as indicated:

BIBLIOGRAPHIC DATA

1. Applicant information is being modified.

SIXTH applicant ABRAHAM VEEFKIND

Citizenship Dutch

Residence Willem Alexanderpark 17, NL-2202 XW Noordwijk, The Netherlands

2. Assignee information is being added.

The assignee of this application is:

ASML NETHERLANDS B.V.

De Run 6501, NL-5504 DR Veldhoven, The Netherlands

Extent of interest of assignee in application: ENTIRE RIGHT, TITLE AND INTEREST

Date: July 1, 2004

PILLSBURY WINTHROP LLP
P.O. Box 10500
McLean, VA 22102
Customer No. 00909



Signature of Practitioner
Emily T. Bell
Registration No. 47418
(703) 905-2261